

Experiments with a Fast Chopper System for Intense Ion Beams

Hannes Dinter

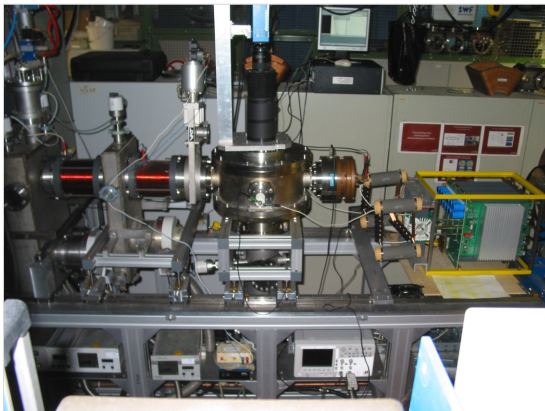
NNP AG, IAP Frankfurt

Monday, 7 March 2011

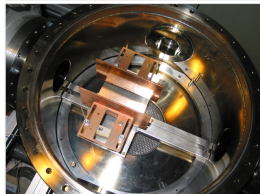
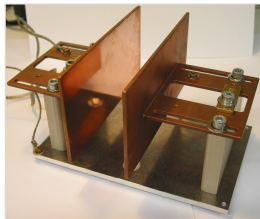
Overview

- Experiments at deflector test stand successfully completed
 - Static deflection: good agreement with analytical results and PIC simulation
 - Successful pulsed mode operation
- Next steps for the FRANZ chopper
 - Deflection plate mounting (protection against sputtering)
 - Electrical connection of the pulse generator
 - Transmission of the deflection pulse into the chopper chamber
 - Secondary particles?

Test Stand Layout



Beam line and High Voltage pulse generator.



Deflection plates.

He^+ beam, $W_B = 20 \text{ keV}$, $I_B = 1 \text{ mA}$; plate distance $d = 7.6 \text{ cm}$.

Static Deflection – Deflection Angle

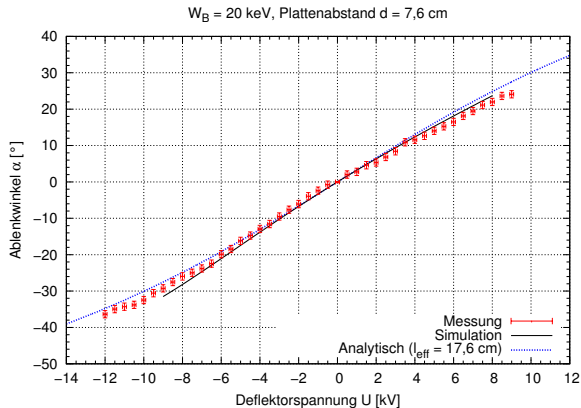
of a He^+ beam with the energy $W_B = 20 \text{ keV}$



$U_L = U_R = 0 \text{ kV}$



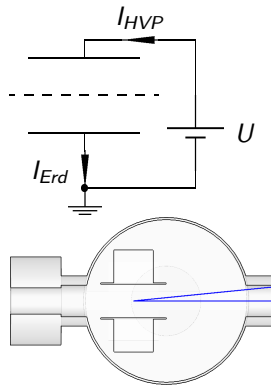
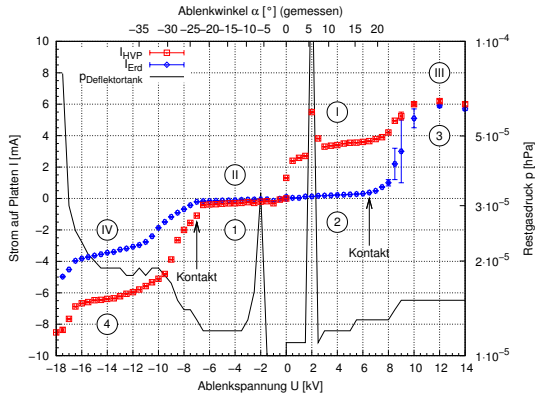
$U_L = +6,5 \text{ kV}, U_R = 0 \text{ kV}$



- Mismatch at the edges (beam close to the deflection plates)
- Asymmetry positive / negative → **mapping characteristics**

Static Deflection – Secondary Particles

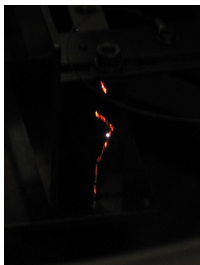
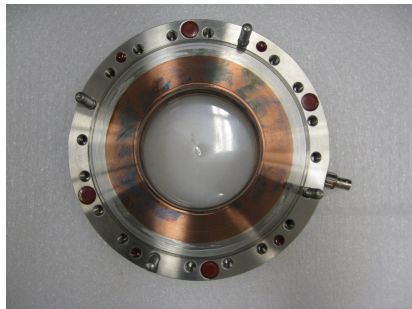
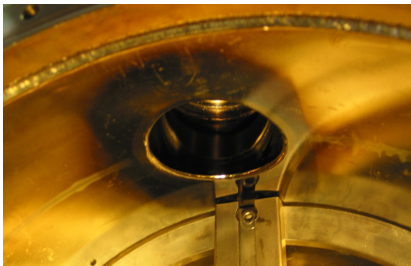
measurement with a He^+ beam at the energy $W_B = 20 \text{ keV}$



Peak in the residual gas pressure at $\alpha = 5.7^\circ \rightarrow$ lower right image

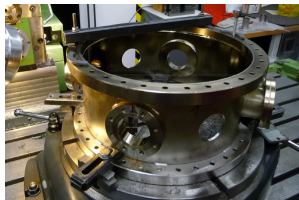
Sputtering

Beam hits plates and walls, releases metal ions → deposition on insulator surfaces



- High Voltage breakdowns
- Plans: new plate mounting
 - Shadowing
 - Meandering
 - New plate material?

New 45 Degree Deflection Ports

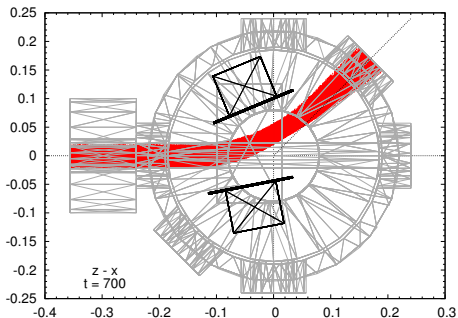


Assembly in the workshop.



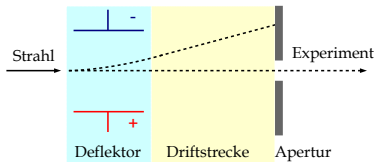
Wheel ion-optical bench.

First beam dynamics simulations using the new setup (preliminary):

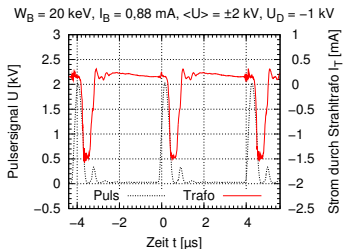


$U_L = -13 \text{ kV}$, $U_R = +12 \text{ kV}$, $W_B = 20 \text{ keV}$
Redistribution: mapping characteristics

Pulsed Mode Operation



Experimental setup.

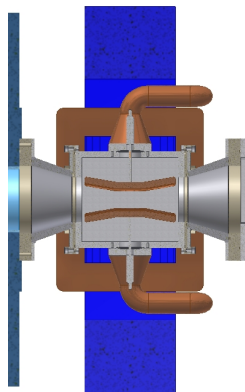


Pulse (black), resulting beam current behind aperture (red).

Pulsing the deflection voltage at $f_0 = 250 \text{ kHz}$, up to $U = \pm 5.6 \text{ kV}$

- Symmetrical wiring of deflection plates, minimising capacitance and voltage breakdowns
- Measuring time of flight and plateau length while varying pulse amplitude, beam energy
- Influence of secondary particles on the system
 - Dump on potential
 - Solution: secondary electron suppression
- Emission of pulse signal

Transmission of Pulse Signal



Cross-sectional view,
actual cable design.

Large influence of pulse signal
on a radio at 4 m distance

- Shielding the environment from pulse signal necessary
 - Protection of the cable against external disturbances
- Coaxial build-up (copper tube)

Parasitic capacitance $C_K = \frac{2\pi\epsilon_0\epsilon_r l}{\ln\left(\frac{R}{r}\right)}$

- Air as dielectric ($\epsilon_r = 1$)
- Short transmission distance l
- Large radius ratio $\frac{R}{r}$

Outlook

- Wiring between pulse generator and chopper chamber
- Parasitic capacitances in acceptable range
- Consideration of sputtering in beam dynamics calculations
- Consequences for the design of the chopper chamber
 - Plate mounting
 - Plate material
 - Secondary electron suppression
- Emittance measurements of deflected beam

Outlook

- Wiring between pulse generator and chopper chamber
- Parasitic capacitances in acceptable range
- Consideration of sputtering in beam dynamics calculations
- Consequences for the design of the chopper chamber
 - Plate mounting
 - Plate material
 - Secondary electron suppression
- Emittance measurements of deflected beam

Thank you for your attention!